

Abstract Of The Disclosure

An interferometric measuring device for measuring the surface of an object by depth scanning, having a short-coherent light source, the emitted light of which is guided to a beam splitter for producing an object beam which is directed via an object beam path to the object and a reference beam which is directed via a reference beam path to a reference surface, having an image recorder for recording the light reflected by the object surface and by the reference surface and combined for interference, and having an evaluation device for determining the surface shape. A white light interferometer without mechanical actuating mechanisms for depth scanning is obtained by placing at least one active optical element that may be influenced by an electrical and/or magnetic field in the object beam path and/or the reference beam path, it being possible to use it to change the optical length of the object light path in relation to the optical length of the reference light path for the depth scanning.